Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	476	dip$4 with (etch$3 clean$3 wash$3 rins$3) with (wafer semicondcutor)	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36
L2	114147	(rotat$3 turn$3 spin$4 pivot$4) with (hold$3 support$3 chuck$3) same (slid$3 vertical$2 up dip$4)	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36
L3	1427	((rotat$3 turn$3 spin$4 pivot$4) with (hold$3 support$3 chuck$3) same (slid$3 vertical$2 up dip$4)) same (wafer semiconductor)	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36
L4	790	dip$4 with (etch$3 clean$3 wash$3 rins$3) with (wafer semiconductor)	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36
L5	17	3 and 4	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36